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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Sujit Sharan and Gurtej S. Sandhu

Serial No.: 09/825,613

Filed: April 3, 2001

For: METHOD FOR PECVD DEPOSITION OF SELECTED
MATERIAL FILMS

§
§ Group Art Unit: 2829
§
§ Examiner: Lisa A Kilday
§
§ Atty. Docket: 95-0716.03
§
§
§

2829
J.B.
J. Steptae
6-24-02
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JUN 14 2002
TECHNOLOGY CENTER 2800

FIRST AMENDMENT AND RESPONSE TO THE OFFICE ACTION OF MARCH 7, 2002

Commissioner for Patents
Washington, D.C. 20231

Certificate of Mailing (37 C.F.R. § 1.8)

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail, postage prepaid, in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231, on the date below:

6/6/02
Date

Susan Jerome
Signature

Dear Sir:

Applicants herein respond to the Office Action of March 7, 2002. Please amend the above-captioned application as follows.

IN THE SPECIFICATION:

Please amend the following Specification paragraphs to the form described below.

31 [0000] This application is a continuation of application serial number 09/249,478, filed Feb. 12, 1999 and issued as U.S. Pat. No. 6,291,341.

[0027] For the purposes of describing one particular embodiment of the invention, it is assumed that a deposition process is to be carried out within the PECVD system 10 described in